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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**  
Norio KIMURA et al. : Docket No. 2001-0660A  
Serial No. 09/864,208 : Group Art Unit 1763  
Filed May 25, 2001 : Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS  
AND SUBSTRATE POLISHING METHOD

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**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of November 17, 2004, kindly amend the above-referenced U.S. patent application as follows:

**THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975**